1_SiO2_dep						
SUBROUTINE	**STEPS**					
Ignite	**Ignite_HiV_00_Asst**					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=shutoff	Beam at step=ExtractBeam			
		Beam at end=shutoff	Beam at end=PlasmaOnly			
		PBN=off	PBN=on			
		Beam voltage=0	Beam voltage=900	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=0	Beam curent=160	**Si**	**20sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=0	Ignition RF Power=150			
		Suppressor Voltage=0	Suppressor Voltage=180			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=0	K Factor=3.1			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	O2=0			
		N2=0	N2=0			
	Ignite_HiV_01_DepoAsst					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=ExtractBeam	Beam at step=ExtractBeam			
		Beam at end=ExtractBeam	Beam at end=ExtractBeam			
		PBN=on	PBN=on			
		Beam voltage=1120	Beam voltage=900	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=200	Beam curent=200	**Si**	**20sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=150	Ignition RF Power=150			
		Suppressor Voltage=150	Suppressor Voltage=180			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=3.1	K Factor=3.1			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	O2=0			
		N2=0	N2=0			
	Ignite_GridClean					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=ExtractBeam	Beam at step=ExtractBeam			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Beam voltage=50	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=310	Beam curent=310	**Si**	**300sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=250	Ignition RF Power=250			
		Suppressor Voltage=800	Suppressor Voltage=800			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	**Gas Values**	Trget angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	Xe=0			
		N2=0	N2=0			

Warmup	**Warm up**					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=50	Beam voltage=55	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=380	Beam curent=400	**Si**	**10sec**	Fixture Rotation Speed=10rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=800	Suppressor Voltage=795			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	O2=0			
		N2=0	N2=0			
SiO2_GasRamp	**SiO2_GasRamp**					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=55	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=380	Beam curent=400	**Si**	**15sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=795			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=5	Ar=5			
		Xe=5	O2=5			
		N2=0	N2=0			
SiO2_PrepSputt	**SiO2_PreDep1_Gas Stab.**					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=380	Beam curent=310	**Si**	**60sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=800			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=5	O2=20			
		N2=0	N2=0			
	SiO2_PreDep2_Sputter					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=380	Beam curent=310	**Si**	**300sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=800			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			

		Ar=0	Ar=0			
		Xe=5	O2=20			
		N2=0	N2=0			
SiO2_Dep	**SiO2_Dep**					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=ExtractOnly	Beam at step=ExtractOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Beam voltage=1120	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=380	Beam curent=310	**Si**	**1800sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=800			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=open
		K Factor=2	K Factor=2			target=open
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=5	O2=20			
		N2=0	N2=0			
SiO2_GasRamp	**SiO2_GasRamp**					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=55	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=380	Beam curent=400	**Si**	**15sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=795			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=5	Ar=5			
		Xe=5	O2=5			
		N2=0	N2=0			
SiO2_GridClean	**SiO2_GridClean**					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=ExtractOnly	Beam at step=ExtractOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Beam voltage=50	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=310	Beam curent=310	**Si**	**300sec**	Fixture Rotation Speed=20rpm
		Ignition RF Power=375	Ignition RF Power=375			
		Suppressor Voltage=800	Suppressor Voltage=800			**Shutter "at beam"**
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	Xe=0			
		N2=0	N2=0			

Shut_n_pmp_dv	Shut_n_pmp_dwn					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=shutoff	Beam at step=shutoff			
		Beam at end=shutoff	Beam at end=shutoff			
		PBN=off	PBN=off			
		Beam voltage=0	Beam voltage=0	PM1	Process time	Fixture Tilt Angle=40
		Beam curent=0	Beam curent=0	**Si**	**30sec**	Fixture Rotation Speed=10rpm
		Ignition RF Power=0	Ignition RF Power=0			
		Suppressor Voltage=0	Suppressor Voltage=0			**Shutter "at beam"**
		PBN Flowrate=0	PBN Flowrate=0			substrate=close
		K Factor=0	K Factor=0			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=0	Xe=0			
		N2=0	N2=0			
	Shut_dwn_open_cryo					
		Depo Beam Parameters	**Assist Beam Parameters**	**Target**	**Process**	**Fixture**
		Beam at step=shutoff	Beam at step=shutoff			
		Beam at end=shutoff	Beam at end=shutoff			
		PBN=off	PBN=off			
		Beam voltage=0	Beam voltage=0	PM1	Process time	Fixture Tilt Angle=90
		Beam curent=0	Beam curent=0	**Si**	**10sec**	Fixture Rotation Speed=10rpm
		Ignition RF Power=0	Ignition RF Power=0			
		Suppressor Voltage=0	Suppressor Voltage=0			**Shutter "at beam"**
		PBN Flowrate=0	PBN Flowrate=0			substrate=close
		K Factor=0	K Factor=0			target=close
		Gas Values	**Gas Values**	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=0	Xe=0			
		N2=0	N2=0			